

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: H. MIURA et al.  
Serial No.: Rule 1.53(b) Continuation of U.S. Patent Application  
Serial No. 09/893,980 filed June 29, 2001  
Filed: July 25, 2003  
For: SEMICONDUCTOR MEMORY DEVICE  
Art Group of Parent: 2818  
Examiner of Parent: Long K. Tran

**INFORMATION DISCLOSURE STATEMENT  
UNDER 37 C.F.R. §1.97 AND §1.98**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

July 25, 2003

Sir:

This Information Disclosure Statement is being filed in accordance with 37 C.F.R. §1.97 along with a Form PTO-1449. This Information Disclosure Statement is being filed simultaneously with the filing of this application.

This application claims priority under 35 U.S.C. §120 from parent Application Nos. 09/893,980, filed June 29, 2001, 08/838,259, filed April 17, 1997, and 08/270,472, filed July 5, 1994. Thus, in accordance with 37 C.F.R. §1.98(d), copies of the references cited or submitted in the parent applications do not need to be filed by the applicant.

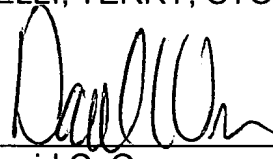
It is respectfully requested that this Information Disclosure Statement be considered by the Examiner.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to the deposit account of Antonelli, Terry, Stout & Kraus, Deposit Account No. 01-2135 (500.33045CC3) and please credit any excess fees to such Deposit Account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP

By

A handwritten signature in black ink, appearing to read "David C. Oren", written over a horizontal line.

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Substitute for form 1449A/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(use as many sheets as necessary)</i>		<b>Complete if Known</b>			
		Application Number			
		Filing Date	July 25, 2003		
		First Named Inventor	MIURA et al.		
		Art Unit	Unassigned		
Examiner Name	Unassigned				
Sheet	1	of	1	Attorney Docket Number	500.33045CC3

U.S. PATENT DOCUMENTS						
Examiner Initials <sup>*</sup>	Cite No. <sup>1</sup>	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)				
		US-4,839,306		06/1989	Wakamatsu	
		US-4,842,675		06/1989	Chapman et al.	
		US-4,860,070		08/1989	Arimoto et al.	
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		US-5,461,248		10/1995	Jun	

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Examiner Initials <sup>1</sup>	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Country	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup> –Number <sup>4</sup> –Kind Code <sup>5</sup> (if known)				
		JP 3-96249	04/1991	Japan (Abstract only)		
		JP 3-236283	10/1991	Japan		
		JP 4-127433	04/1992	Japan (Abstract only)		

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Examiner Signature	Date Considered
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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